BS EN 62047-13:2012

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Semiconductor devices — Micro-electromechanical devices

Part 13: Bend- and shear- type test methods of measuring adhesive strength for MEMS structures

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English version

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(IEC 62047-13:2012)

Dispositifs à semiconducteurs - Dispositifs microélectromécaniques - Partie 13: Méthodes d'essais de types courbure et cisaillement de mesure de la résistance d'adhérence pour les structures MEMS
(CEI 62047-13:2012)

Halbleiterbauelemente - Bauelemente der Mikrosystemtechnik - Teil 13: Biege- und Scherprüfverfahren zur Messung der Haftfestigkeit bei MEMS-Strukturen
(IEC 62047-13:2012)

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Foreword

The text of document 47F/109/FDIS, future edition 1 of IEC 62047-13, prepared by SC 47F, "Micro-electromechanical systems", of IEC TC 47, "Semiconductor devices" was submitted to the IEC-CENELEC parallel vote and approved by CENELEC as EN 62047-13:2012.

The following dates are fixed:

• latest date by which the document has to be implemented at national level by publication of an identical national standard or by endorsement	(dop)	2013-01-03
• latest date by which the national standards conflicting with the document have to be withdrawn	(dow)	2015-04-03

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Annex ZA
(normative)
Normative references to international publications with their corresponding European publications

The following documents, in whole or in part, are normatively referenced in this document and are indispensable for its application. For dated references, only the edition cited applies. For undated references, the latest edition of the referenced document (including any amendments) applies.

NOTE When an international publication has been modified by common modifications, indicated by (mod), the relevant EN/HD applies.

Publication	Year	Title	EN/HD	Year
IEC 62047-2	2006	Semiconductor devices - Micro-electromechanical devices - Part 2: Tensile testing methods of thin film materials	EN 62047-2	2006

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